

ATES PATENT AND TRADEMARK OFFICE

Applicant: Koichiro Tanaka

Art Unit : 2822

Serial No.: 09/842,797

Examiner: Maria F. Guerrero

Filed

: April 27, 2001

Title

: METHOD OF FABRICATING SEMICONDUCTOR DEVICE

MAIL STOP AMENDMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Applicants request consideration of the references listed on the attached PTO-1449 form. Under 37 C.F.R. § 1.98 (a)(2)(ii), only copies of foreign patent documents and/or non-patent literature are enclosed. Copies of any U.S. patents or U.S. patent application publications can be provided upon request.

This statement is being filed after a first Office action on the merits, but before receipt of a final Office action or a Notice of Allowance. A check for \$180 in payment of the late submission fee of §1.17(p) is enclosed. Please apply any other charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date:

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Substitute Form PTO-1449 (Modified)

J.S. Department of Commerce Patent and Fademark Office

Attorney's Docket No. 12732-034001

Application No. 09/842,797

Information Disclosure Statement

by Applicant (Use several sheets if necessary)

Koichiro Tanaka

Applicant

Group Art Unit

(37 CFR §1.98(b))

Filing Date April 27, 2001 2822

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	4,439,245	03/27/1984	WU			01/25/1982
	AB				_		
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner	Desig.	Document	Publication	Country or			Trans	slation
Initial	ID	Number	Date	Patent Office	Class	Subclass	Yes	No
	AL							
	AM	•						
	AN							
	AO							
	AP							

	Other Documents (include Author, Title, Date, and Place of Publication)					
Examiner	Desig.					
Initial	ID	Document				
	AQ	Hayashi et al., "FABRICATION OF LOW-TEMPERATURE BOTTOM-GATE POLY-SI TFTS ON LARGE-AREA SUBSTRATE BY LINEAR-BEAM EXCIMER LASER CRYSTALLIZATION AND ION DOPING METHOD," IEDM '95; Technical Digest of International Electron Devices Meeting, 33.3.1 – 33.3.4, pp. 829-832, December 10-13, 1995.				
	AR					
	AS					
	AT					

Examiner Signature	Date Considered			
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.				